Application No.: 10/534,411 Docket No.: 3273-0202PUS1

Reply to Office Action of December 31, 2009

## AMENDMENTS TO THE ABSTRACT OF THE DISCLOSURE

Please substitute the Abstract of the Disclosure with the attached Abstract. The following changes have been made to the Abstract:

A method of the invention produces a porous film by casting a polymer solution containing a polymer onto a substrate to form a film, and subjecting the film to phase conversion to thereby form a porous film. In the method, the polymer constituting the porous film has a surface tension Sa [mN/m], the substrate has a surface tension Sb [mN/m], and Sa and Sb satisfy the following condition: Sa Sb≥ 10. This method can produce a porous film having a high rate of hole area at its surfaces and having homogenous micropores from the surfaces to the core thereof. A porous film of the invention is a porous film having a large number of continuous micropores. The film has a thickness of 5 to 200 µm, has an average surface pore size A of 0.01 to 10 µm, [[and]] an average surface porosity rate of surface hole area C₁ and has an average inside pore size B and an average inside porosity rate of inside hole area D₁ inside thereof, in which the The ratio A/B of A to B is 0.3 to 3₂, and the ratio C/D of C to D is 0.7 to 1.5. The porous film is produced by casting a polymer solution containing a polymer onto a substrate to form a film and subjecting the film to phase conversion to thereby form a porous film. In the method, the polymer constituting the porous film has a surface tension Sa [mN/m], the substrate has a surface tension Sb [mN/m], and Sa and Sb satisfy the following condition: Sa-Sb≥-10.

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